

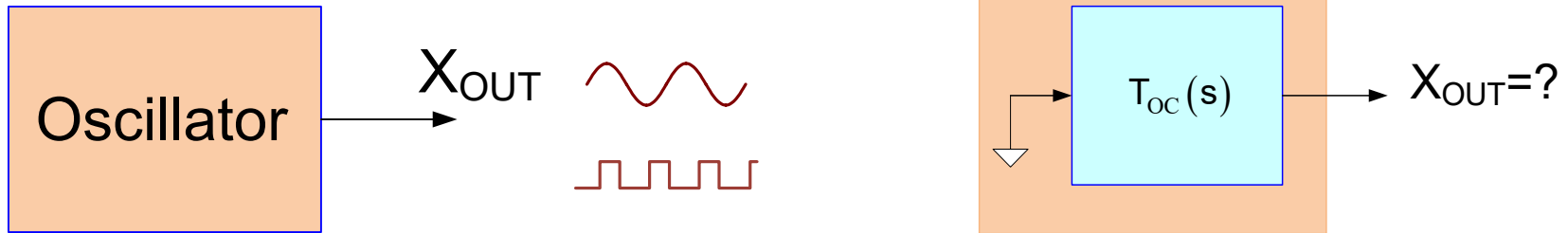
# EE 508

## Lecture 35

### High Frequency Filters

Review from last lecture

# What is the relationship, if any, between a filter and an oscillator or VCO?



- When power is applied to an oscillator, it initially behaves as a small-signal linear network
- When operating linearly, the oscillator has poles (but no zeros)
- Poles are ideally on the imaginary axis or appear as cc pairs in the RHP
- There is a wealth of literature on the design of oscillators
- Oscillators often are designed to operate at very high frequencies
- If cc poles of a filter are moved to RHP it will become an oscillator
- **Can oscillators be modified to become filters?**

Review from last lecture

# Consider the following 3-pole situation

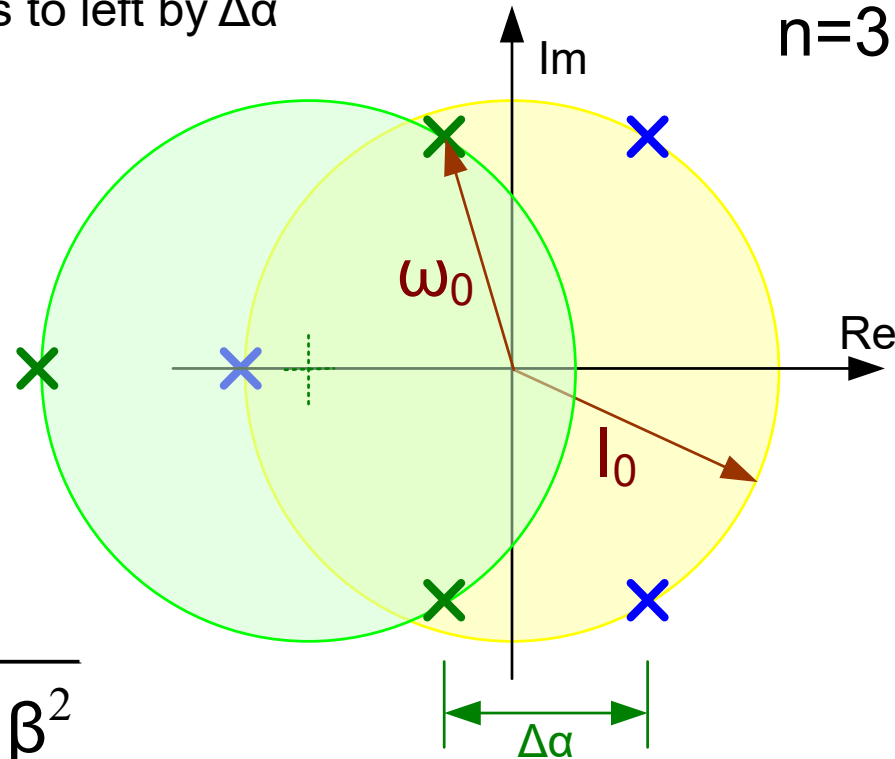
Poles of  $D(s) = s^n + I_0^n$

Consider moving all poles to left by  $\Delta\alpha$

$$\beta = 0.866 I_0$$

$$\alpha = 0.5 I_0 - \Delta\alpha$$

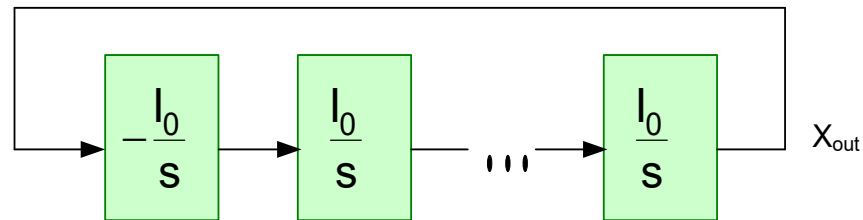
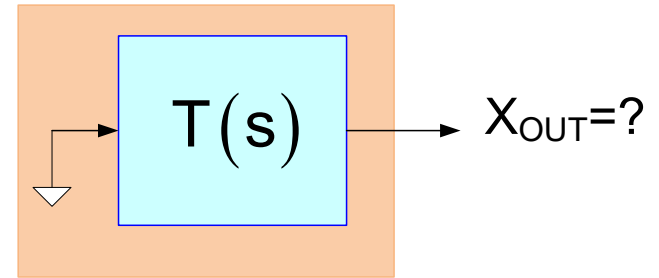
$$\omega_0 = \sqrt{(\alpha - \Delta\alpha)^2 + \beta^2}$$



So, to get a high  $\omega_0$ , want  $\beta$  as large as possible

Review from last lecture

Consider a cascaded integrator loop comprised of  $n$  integrators



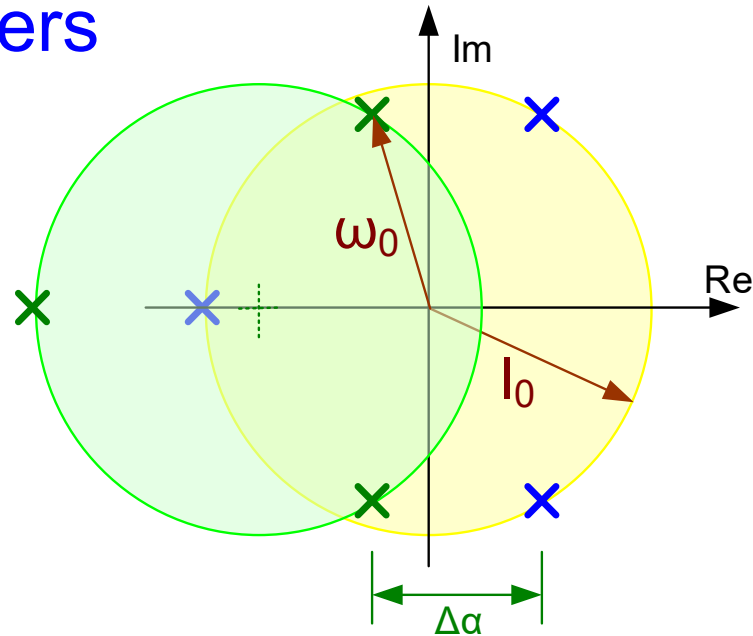
$$X_{OUT} = -\left(\frac{I_0}{s}\right)^n X_{OUT}$$

$$X_{OUT} (s^n + I_0^n) = 0$$

$$D(s) = s^n + I_0^n$$

# Review from last lecture

## VCO Derived Filters



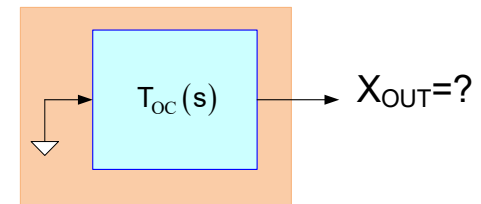
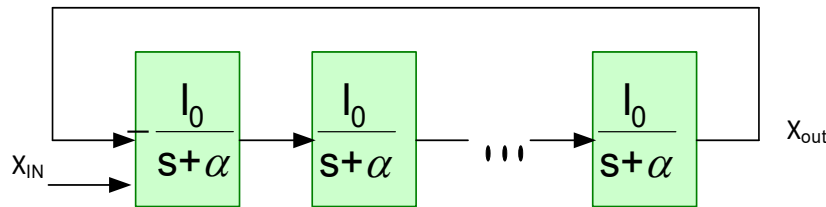
- Most if not all oscillators can be modified to form a narrow-band band-pass filter
- Modification involves
  - ✓ adding loss so that the pole-pair with the largest real component is in the LHP
  - ✓ Introducing input to form a filter
- Can provide new filter architectures and benefit from desirable properties of the oscillator
- High frequency filters can be obtained from high frequency oscillators

## Review from last lecture

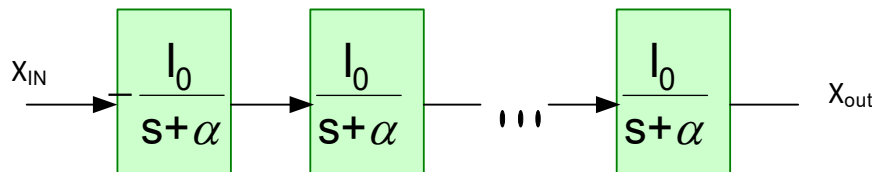
# Inputs to Oscillator-Derived Filters:

Most applicable to designing 2<sup>nd</sup>-order high frequency narrow band filters

- Add loss to delay stages
- Multiple Input Locations Often Possible
- Natural Input is Input to delay stage



- Add loss to delay stages
- Often Just Salvage Stages (drop feedback loop)
- Natural input is input to delay stage



# High Frequency Filter Design

- Architecture selection is critical
- At high frequencies, simplicity of the structures is important
- Parasitic capacitances and their relationship to the time constants that can be achieved provide the ultimate limit on speed
- Will limit discussions to “inductorless” structures

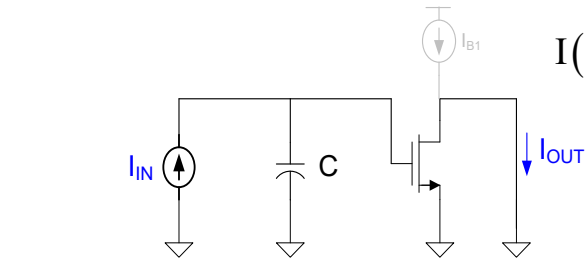
# High Frequency Filter Design

Following two methods will provide highest frequency of operation

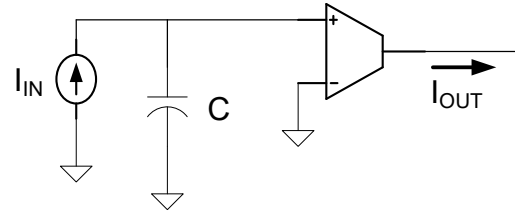
- Degenerate VCOs
- Simple high-frequency integrator-based filters



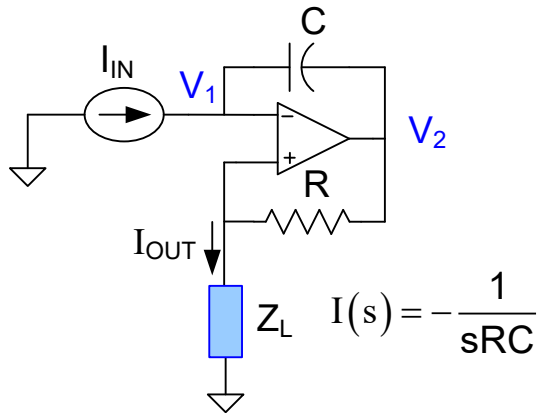
# Integrator Architecture Selection



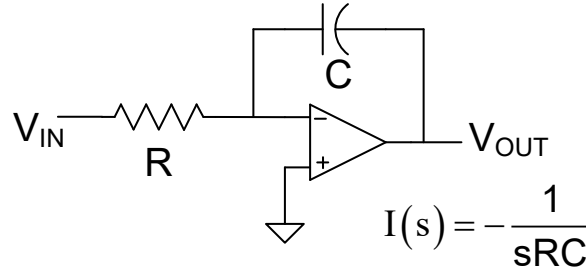
$$I(s) = -\frac{g_m}{sC}$$



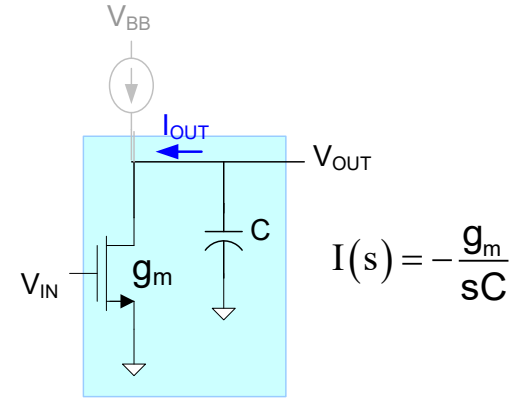
$$I(s) = \frac{g_m}{sC}$$



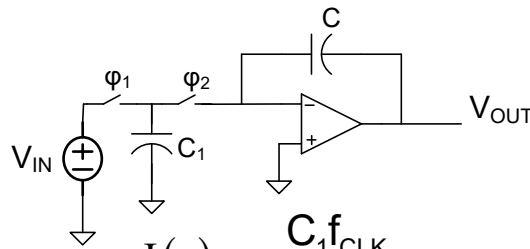
$$I(s) = -\frac{1}{sRC}$$



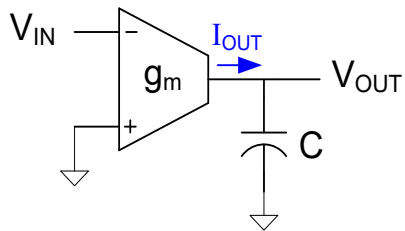
$$I(s) = -\frac{1}{sRC}$$



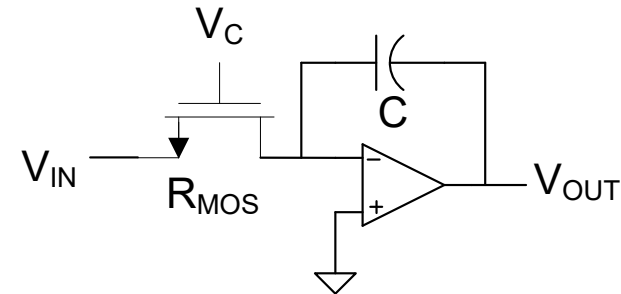
$$I(s) = -\frac{g_m}{sC}$$



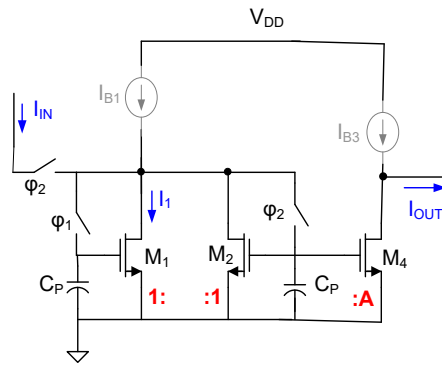
$$I(s) = -\frac{C_1 f_{CLK}}{sC}$$



$$I(s) = -\frac{g_m}{sC}$$



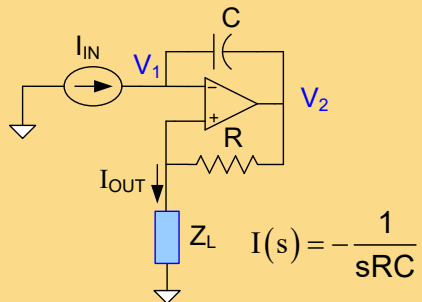
$$I(s) = -\frac{1}{sR_{MOS}C}$$



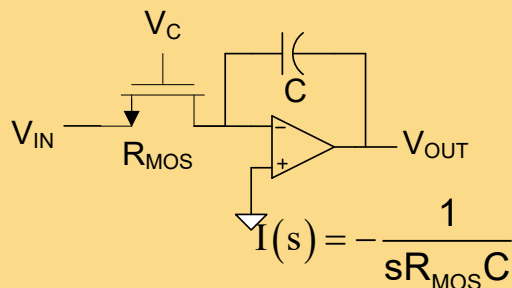
$$I(s) = -\frac{Af_{CLK}}{s}$$

# Integrators for High-Speed Operation

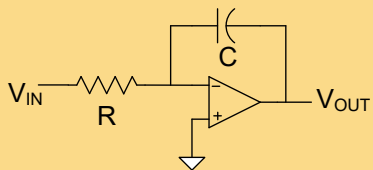
Slow



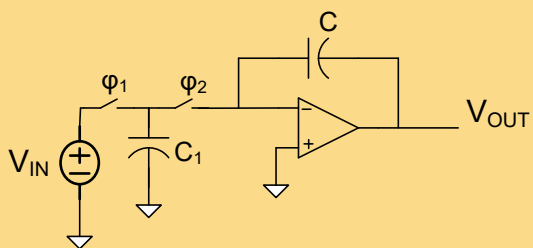
$$I(s) = -\frac{1}{sRC}$$



$$I(s) = -\frac{1}{sR_{MOS}C}$$

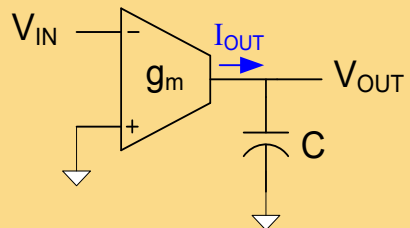


$$I(s) = -\frac{1}{sRC}$$

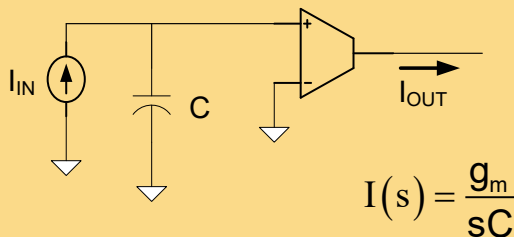


$$I(s) = -\frac{C_1 f_{CLK}}{sC}$$

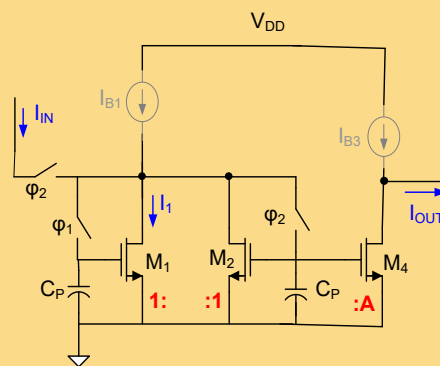
Reasonably Fast



$$I(s) = -\frac{g_m}{sC}$$

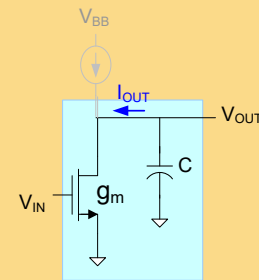


$$I(s) = \frac{g_m}{sC}$$

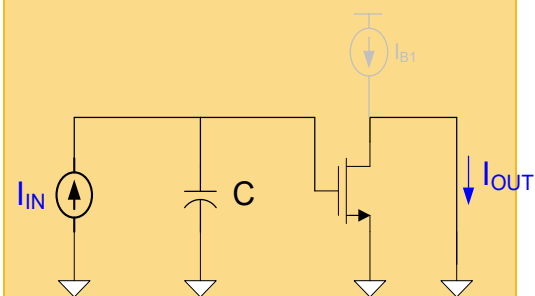


$$I(s) = -\frac{Af_{CLK}}{s}$$

Very Fast



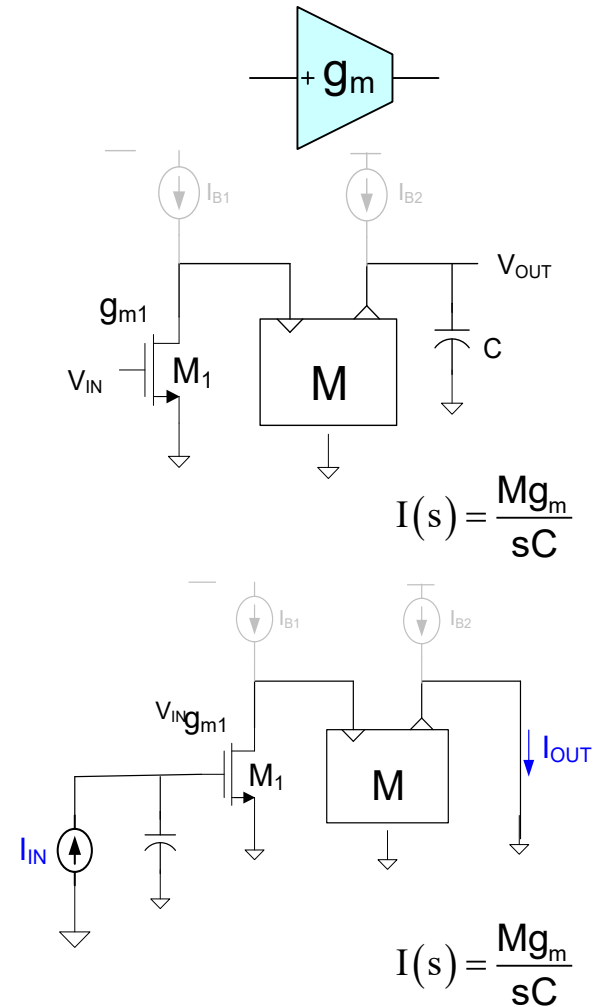
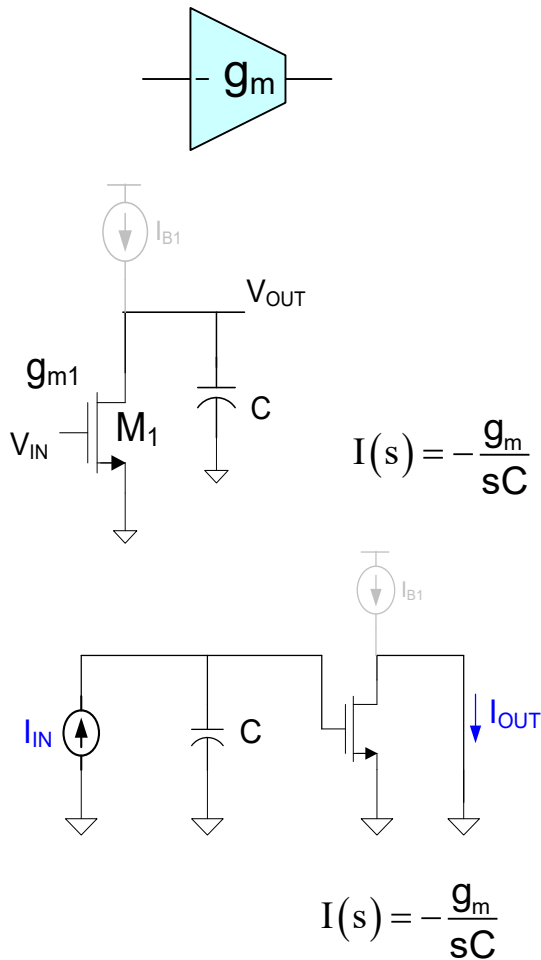
$$I(s) = -\frac{g_m}{sC}$$



$$I(s) = -\frac{g_m}{sC}$$

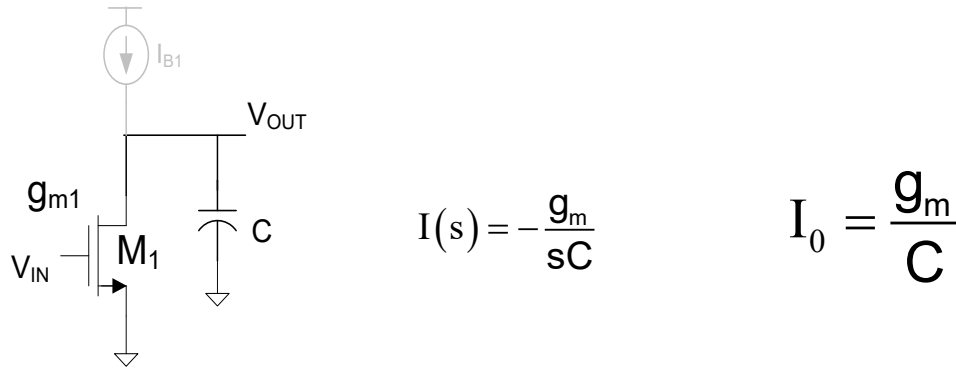
# Single-ended High-Frequency TA Integrators

Structures of choice for highest-frequency of operation



Some authors focus on voltage mode and others on current mode  
But overall structures and performance appears to be identical

# Single-ended High-Frequency TA Integrators



Recall:  $\omega_0$  for integrator-based filters generally proportional to  $I_0$

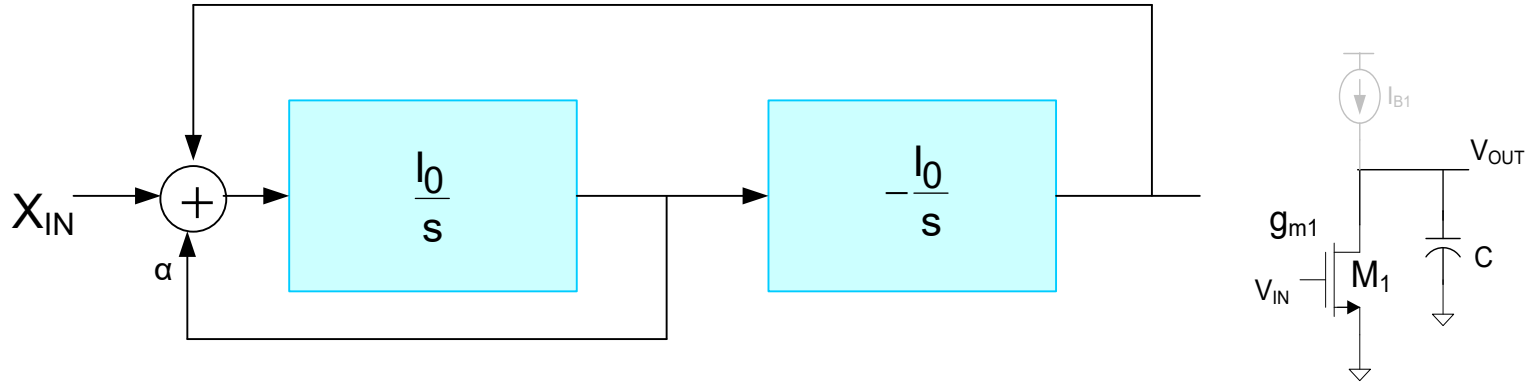
How high can  $I_0$  be?

$$I_0 = \frac{W}{L} \frac{\mu C_{OX} V_{EB}}{C}$$

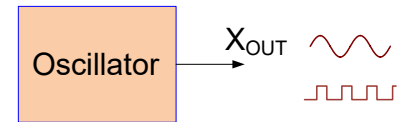
Looks like we can make  $I_0$  as large as we want by making  $V_{EB}$  large,  $C$  small,  $L$  small, and  $W$  large

# Single-ended High-Frequency TA Integrators

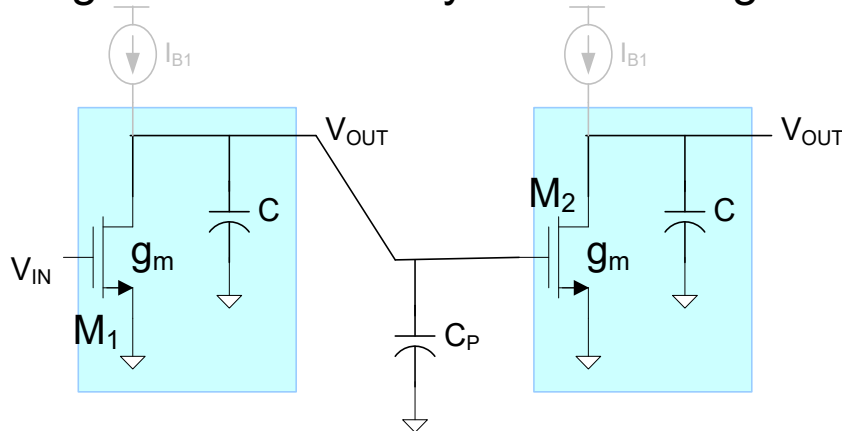
How high can  $I_0$  be?



Consider a typical filter – the two integrator loop



Integrator is loaded by another integrator!



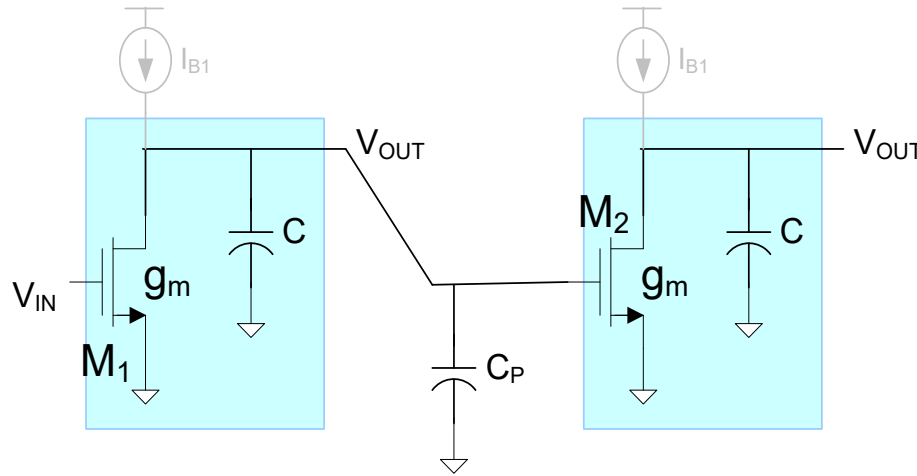
$$I_0 = \frac{W_1}{L_1} \frac{\mu C_{OX} V_{EB1}}{C + C_P + C_{OX} W_2 L_2}$$

Even if  $C$  goes to 0,  $I_0$  is limited!

$C_P$  is the parasitic capacitances on the output node

# Single-ended High-Frequency TA Integrators

How high can  $I_0$  be?



$$I_0 = \frac{W_1}{L_1} \frac{\mu C_{OX} V_{EB1}}{C + C_P + C_{OX} W_2 L_2}$$

Setting  $C$  to 0 and assuming  $C_p$  is small,

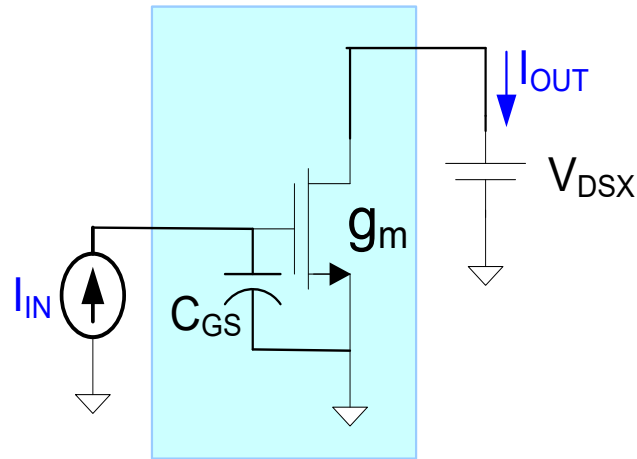
$$I_0 = W_1 / L_1 \frac{\mu C_{OX} V_{EB1}}{C_{OX} W_2 L_2}$$

$$I_0 = \frac{\mu W_1 V_{EB1}}{W_2 L_1 L_2}$$

Assuming the integrator stages are identical, it follows that

$$I_0 = \frac{\mu V_{EB1}}{L_{\min}^2}$$

# Transition (transit) frequency ( $f_T$ ) of a process



The transit frequency of a process is the frequency where the short-circuit current gain of the common-source configuration drops to 1.

$$i_{OUT} = g_m v_{gs}$$

$$i_{IN} \cdot \frac{1}{sC_{GS}} = v_{gs}$$

$$\frac{i_{OUT}}{i_{IN}} = \frac{g_m}{sC_{GS}}$$

$$1 = \frac{g_m}{C_{GS} \omega_T}$$

$$\omega_T = \frac{g_m}{C_{GS}} = \frac{\left( \mu C_{OX} \frac{W}{L} V_{EB} \right)}{C_{OX} WL} = \frac{\mu V_{EB}}{L^2}$$

$$\omega_T = \frac{\mu V_{EB}}{L_{min}^2}$$

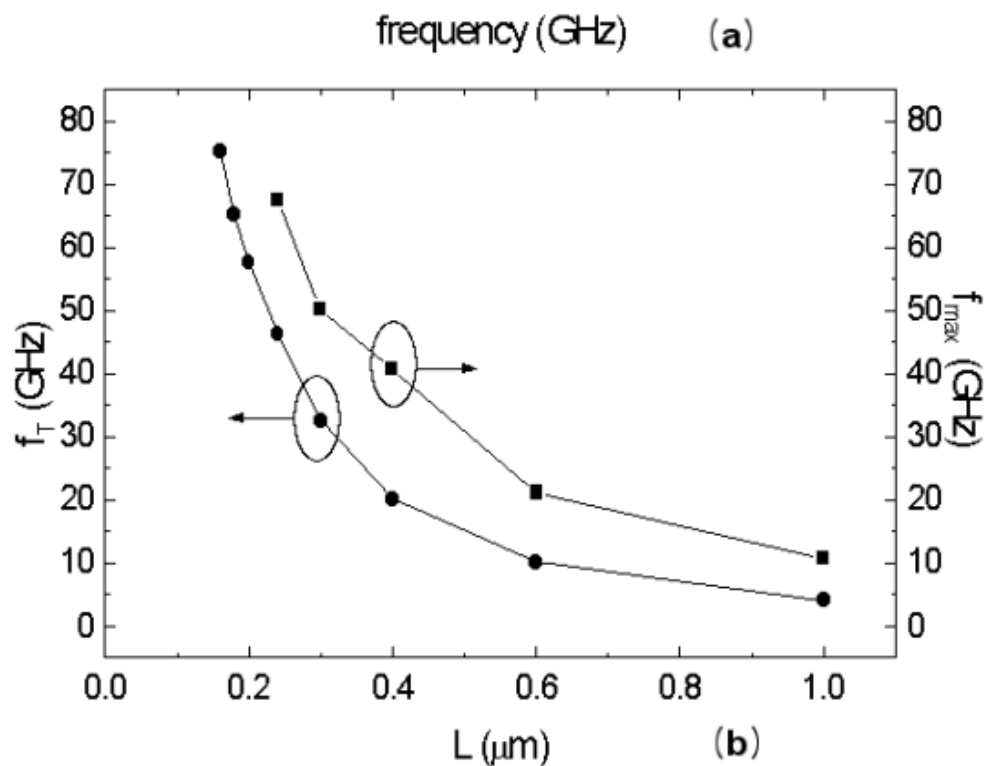
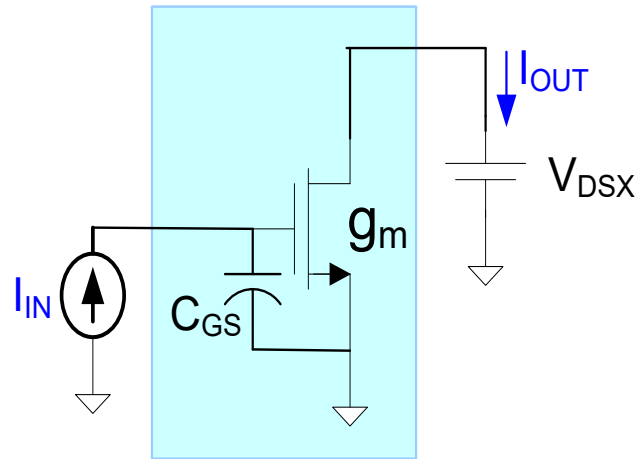


Fig. 7. (a) Maximum stable gain (MSG) and maximum available gain (MAG) for different channel lengths and (b) the cutoff frequency ( $f_T$ ) and maximum oscillation frequency ( $f_{max}$ ) as functions of the channel length.



# Transition (transit) frequency ( $f_T$ ) of a process



The transit frequency of a process is the frequency where the short-circuit current gain of the common-source configuration drops to 1.

$$\omega_T = \frac{\mu V_{EB}}{L_{\min}^2}$$

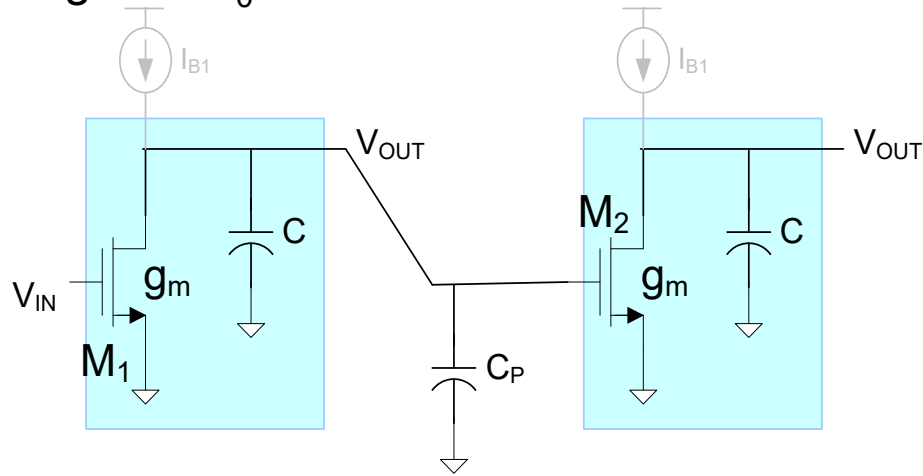
This is dependent upon  $V_{EB}$

Does not include effects of diffusion capacitances or overlap capacitances

$f_{MAX}$  is another figure that characterizes the speed of a process

# Single-ended High-Frequency TA Integrators

How high can  $I_0$  be?



$$I_{0M} = \frac{\mu V_{EB1}}{L_{\min}^2}$$

$$I_{0M} = \omega_T$$

(neglected C and  $C_P$ )

Speed of operation increases with  $V_{EB1}$

$V_{EB1}$  is limited by signal swing requirements and  $V_{DD}$

Symmetric Signal Swing:

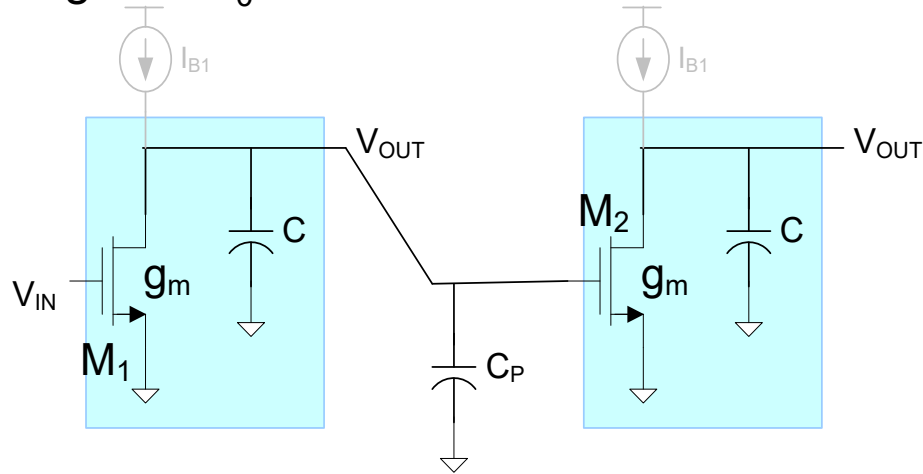
$$V_{SW} \cong \min\{V_{DD} - V_{OQ}, V_{OQ} - (V_T + 100\text{mV})\}$$

$$V_{OQ} = V_T + V_{EB}$$

$$V_{SW} \cong \min\{V_{DD} - V_T - V_{EB}, V_T + V_{EB} - (V_T + 100\text{mV})\}$$

# Single-ended High-Frequency TA Integrators

How high can  $I_0$  be?



$$I_{0M} = \frac{\mu V_{EB1}}{L_{\min}^2}$$

$$I_{0M} = \omega_T$$

Speed of operation increases with  $V_{EB}$

$V_{EB}$  is limited by signal swing requirements and  $V_{DD}$

Signal Swing:

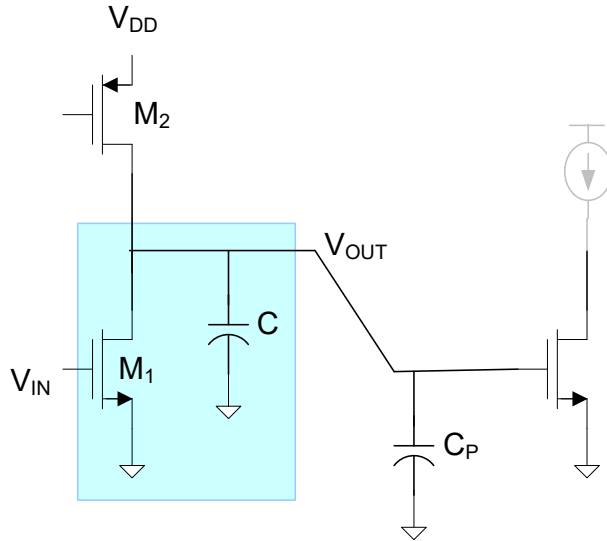
$$V_{DD} - V_T - V_{EB} = V_T + V_{EB} - (V_T + 100\text{mV})$$

$$V_{EB} = \frac{V_{DD} + 100\text{mV} - V_T}{2}$$

$$I_{0MAX} \cong \frac{\mu(V_{DD} + 100\text{mV} - V_T)}{2L_{\min}^2}$$

# Single-ended High-Frequency TA Integrators

How high can  $I_0$  be?



$$I_0 = \frac{\mu C_{OX} W_1 / L_1 V_{EB1}}{C + C_P + C_{OX} W_1 L_1}$$

Neglecting  $C_p$  and  $C$ , obtained

$$I_{0M} = \omega_T$$

$$I_{0M} = \frac{\mu V_{EB1}}{L_{min}^2}$$

Note this is independent of  $W_1$

How much power is required to realize  $I_{0MAX}$ ?

$$P_{QPT} = V_{DD} I_D$$

$$P_{QPT} = V_{DD} \frac{\mu C_{OX} W_1 V_{EB1}^2}{2L_{min}}$$

$$I_{0MAX} \cong \frac{\mu(V_{DD} + 100mV - V_T)}{2L_{min}^2}$$

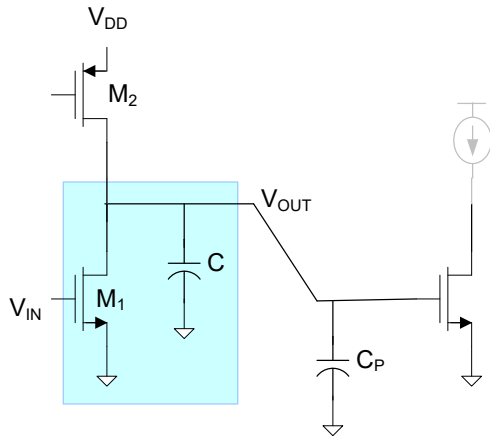
Note this is proportional to  $W_1$

$$P_{QPT} = V_{DD} \frac{\mu C_{OX} W_{min} V_{EB1}^2}{2L_{min}} \stackrel{W_{min}=L_{min}}{\cong} V_{DD} \frac{\mu C_{OX} V_{EB1}^2}{2}$$

$$= V_{DD} \frac{\mu C_{OX}}{2} \left( \frac{V_{DD} + 100mV - V_T}{2} \right)^2 \stackrel{V_T=0.25V_{DD}}{\cong} V_{DD} \frac{\mu C_{OX}}{2} \left( \frac{0.75V_{DD}}{2} \right)^2 \cong .07 \mu C_{OX} V_{DD}^3$$

# Single-ended High-Frequency TA Integrators

How high can  $I_0$  be?



Consider again  $C_p$  and recall:

$$I_0 = \frac{W_1}{L_1} \frac{\mu C_{OX} V_{EB1}}{C + C_P + C_{OX} W_2 L_2}$$

$C_p$  will modestly reduce the speed of the circuit

$$I_0 = \frac{\mu C_{OX} W_1 V_{EB1}}{L_{min} C_P + C_{OX} W_1 L_{min}^2}$$

Consider the diffusion capacitances on  $M_1$  and  $M_2$

$$I_0 = \frac{\mu C_{OX} W_1 V_{EB1}}{L_{min} (C_{P1} + C_{P2}) + C_{OX} W_1 L_{min}^2}$$

$$I_0 = W_1 / L_1 \frac{\mu C_{OX} V_{EB1}}{C + C_P + C_{OX} W_1 L_1}$$

Neglecting  $C_p$  and  $C$ , obtained

$$I_{0M} = \omega_T$$

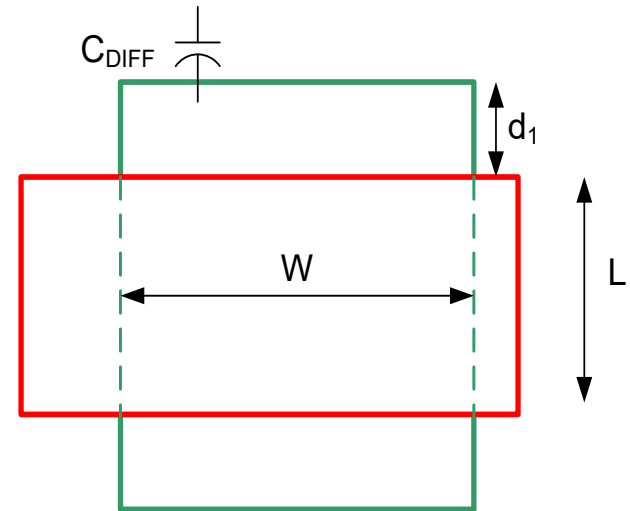
$$I_{0M} = \frac{\mu V_{EB1}}{L_{min}^2}$$

$$I_{0MAX} \cong \frac{\mu (V_{DD} + 100mV - V_T)}{2L_{min}^2}$$

# How high can $I_0$ be?

The parasitic diffusion capacitances are strongly layout dependent

Consider a basic layout of a transistor



The capacitance density along the sw of the drain is usually somewhat less than that along the outer perimeters but may not easily be modeled separately

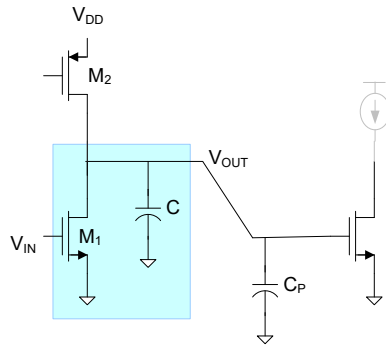
Assuming the same, drain diffusion capacitance of a transistor is given by

$$C_{DIFF} = C_{BOT} [W d_1] + C_{SW} [2d_1 + 2W]$$

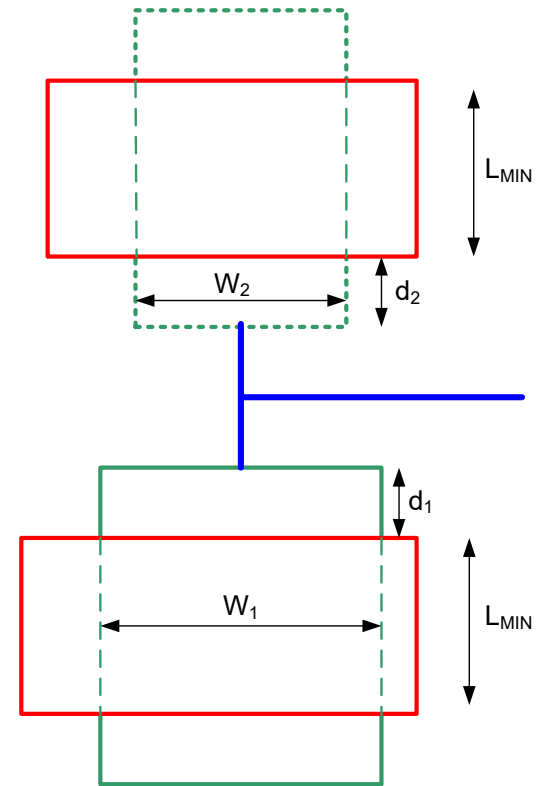
$C_{BOT}$  is the bottom diffusion capacitance density

$C_{SW}$  is the sidewall diffusion capacitance density

# How high can $I_0$ be?



Consider a basic layout



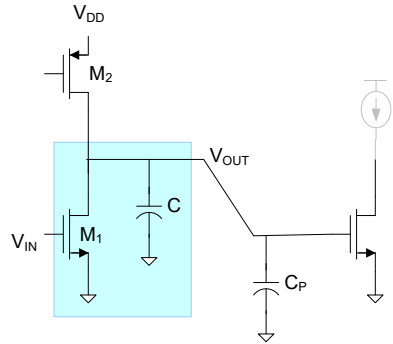
$$I_0 = \frac{\mu C_{OX} W_1 V_{EB1}}{L_{min} (C_{P1} + C_{P2}) + C_{OX} W_1 L_{min}^2}$$

$$I_0 = \frac{\mu C_{OX} W_1 V_{EB1}}{L_{min} (C_{BOTn} [W_1 d_1] + C_{SWn} [2d_1 + 2W_1] + C_{BOTp} [W_2 d_2] + C_{SWp} [2d_2 + 2W_2]) + C_{OX} W_1 L_{min}^2}$$

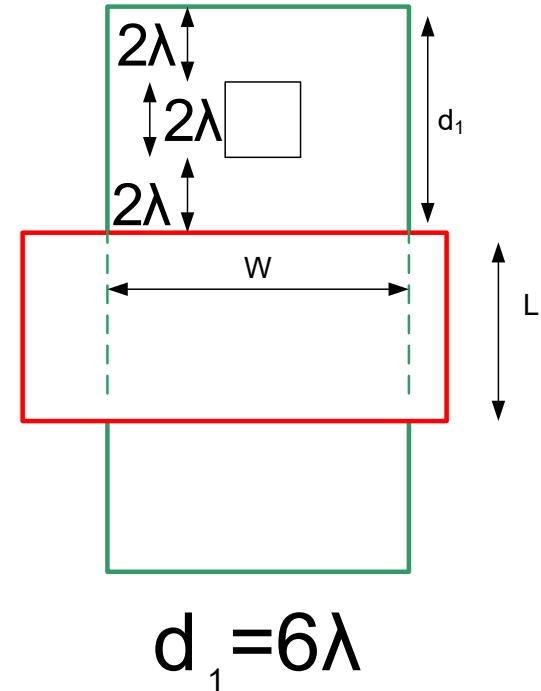
Assume  $L_{MIN} = 2\lambda$

$$I_0 = \frac{\mu C_{OX} W_1 V_{EB1}}{2\lambda (C_{BOTn} [W_1 d_1] + C_{SWn} [2d_1 + 2W_1] + C_{BOTp} [W_2 d_2] + C_{SWp} [2d_2 + 2W_2]) + C_{OX} W_1 4\lambda^2}$$

# How high can $I_0$ be?



Consider a basic layout of a transistor



Assume  $d_1 = 6\lambda$

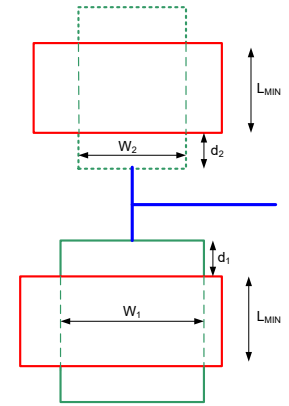
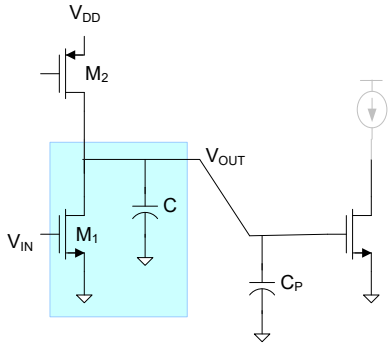
$$I_0 = \frac{\mu C_{OX} W_1 V_{EB1}}{2\lambda (C_{BOTn} [W_1 d_1] + C_{SWn} [2d_1 + 2W_1] + C_{BOTp} [W_2 d_2] + C_{SWp} [2d_2 + 2W_2]) + C_{OX} W_1 4\lambda^2}$$

$$I_0 = \frac{\mu C_{OX} W_1 V_{EB1}}{2\lambda (C_{BOTn} [W_1 6\lambda] + C_{SWn} [12\lambda + 2W_1] + C_{BOTp} [W_2 6\lambda] + C_{SWp} [12\lambda + 2W_2]) + C_{OX} W_1 4\lambda^2}$$



# How high can $I_0$ be?

Consider a basic layout



$$I_0 = \frac{\mu_n C_{OX} W_1 V_{EB1}}{2\lambda (C_{BOTn} [W_1 6\lambda] + C_{SWn} [12\lambda + 2W_1]) + C_{BOTp} [W_2 6\lambda] + C_{SWp} [12\lambda + 2W_2]) + C_{OX} W_1 4\lambda^2}$$

$$I_0 = \frac{\mu_n V_{EB1}}{4\lambda^2 + 2\lambda \left( \frac{C_{BOTn}}{C_{OX}} [6\lambda] + \frac{C_{SWn}}{C_{OX}} \left[ 12 \frac{\lambda}{W_1} + 2 \right] + \frac{C_{BOTp}}{C_{OX}} \left[ \frac{W_2}{W_1} \right] [6\lambda] + \frac{C_{SWp}}{C_{OX}} \left[ 12 \frac{\lambda}{W_1} + 2 \frac{W_2}{W_1} \right] \right)}$$

Define and assume

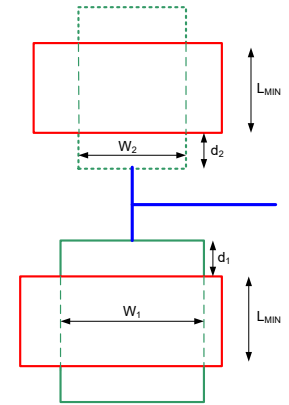
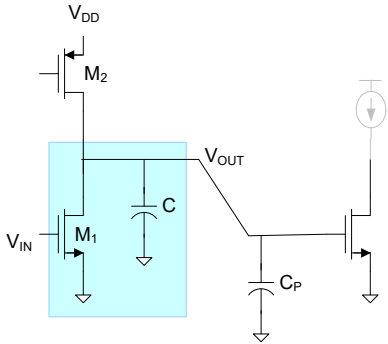
$$h_{BOT} = \frac{C_{BOTn}}{C_{OX}} = \frac{C_{BOTp}}{C_{OX}}$$

$$h_{SW} = \frac{C_{SWn}}{\lambda C_{OX}} = \frac{C_{SWp}}{\lambda C_{OX}}$$

$$I_0 = \frac{\mu_n V_{EB1}}{4\lambda^2 + 2\lambda \left( h_{BOT} [6\lambda] + \lambda h_{SW} \left[ 12 \frac{\lambda}{W_1} + 2 \right] + h_{BOT} \left[ \frac{W_2}{W_1} \right] [6\lambda] + \lambda h_{SW} \left[ 12 \frac{\lambda}{W_1} + 2 \frac{W_2}{W_1} \right] \right)}$$

# How high can $I_0$ be?

Consider a basic layout

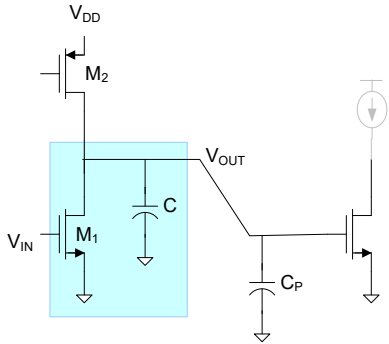


$$I_0 = \frac{\mu_n V_{EB1}}{4\lambda^2 + 2\lambda \left( h_{\text{BOT}} [6\lambda] + \lambda h_{\text{SW}} \left[ 12 \frac{\lambda}{W_1} + 2 \right] + h_{\text{BOT}} \left[ \frac{W_2}{W_1} \right] [6\lambda] + \lambda h_{\text{SW}} \left[ 12 \frac{\lambda}{W_1} + 2 \frac{W_2}{W_1} \right] \right)}$$

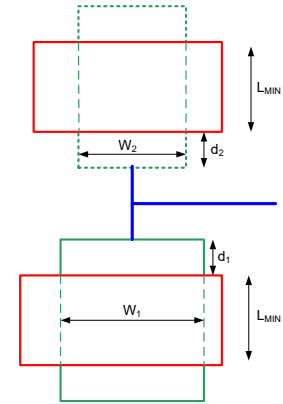
$$I_0 = \frac{\mu_n V_{EB1}}{4\lambda^2 + 4\lambda^2 \left( 3h_{\text{BOT}} \left[ 1 + \frac{W_2}{W_1} \right] + h_{\text{SW}} \left[ 12 \frac{\lambda}{W_1} + 1 + \frac{W_2}{W_1} \right] \right)}$$

$$I_0 = \frac{\frac{\mu_n V_{EB1}}{4\lambda^2}}{1 + \left( 3h_{\text{BOT}} \left[ 1 + \frac{W_2}{W_1} \right] + h_{\text{SW}} \left[ 12 \frac{\lambda}{W_1} + 1 + \frac{W_2}{W_1} \right] \right)}$$

# How high can $I_0$ be?



Consider a basic layout



$$I_0 = \frac{\mu_n V_{EB1}}{4\lambda^2} \frac{1}{1 + \left( 3h_{BOT} \left[ 1 + \frac{W_2}{W_1} \right] + h_{SW} \left[ 12 \frac{\lambda}{W_1} + 1 + \frac{W_2}{W_1} \right] \right)}$$

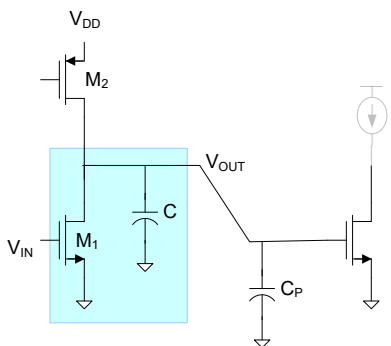
Recall

$$\frac{W_2}{W_1} = \frac{\mu_n}{\mu_p} \left( \frac{V_{EB1}}{V_{EB2}} \right)^2$$

$$\omega_T = \frac{\mu_n V_{EB1}}{4\lambda^2}$$

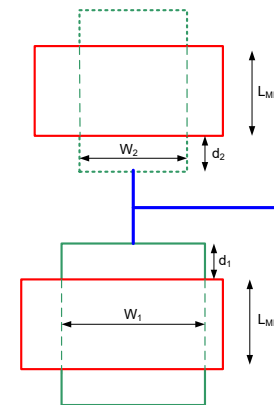
$$I_0 = \frac{\omega_T}{1 + \left( 3h_{BOT} \left[ 1 + \frac{\mu_n}{\mu_p} \left( \frac{V_{EB1}}{V_{EB2}} \right)^2 \right] + h_{SW} \left[ 12 \frac{\lambda}{W_1} + 1 + \frac{\mu_n}{\mu_p} \left( \frac{V_{EB1}}{V_{EB2}} \right)^2 \right] \right)}$$

# How high can $I_0$ be?



$$I_0 = \frac{\omega_T}{1 + \left( 3h_{\text{BOT}} \left[ 1 + \frac{\mu_n}{\mu_p} \left( \frac{V_{\text{EB1}}}{V_{\text{EB2}}} \right)^2 \right] + h_{\text{SW}} \left[ 12 \frac{\lambda}{W_1} + 1 + \frac{\mu_n}{\mu_p} \left( \frac{V_{\text{EB1}}}{V_{\text{EB2}}} \right)^2 \right] \right)}$$

Consider a basic layout



Example: Consider the 0.25u TSMC CMOS Process

$$C_{\text{OX}} = 5.8 \text{ fF}/\mu^2$$

$$C_{\text{SWn}} = .440 \text{ fF}/\mu$$

$$C_{\text{SWp}} = .350 \text{ fF}/\mu$$

$$C_{\text{BOT}} = 1.8 \text{ fF}/\mu^2$$

$$\frac{\mu_n}{\mu_p} = 4.1$$

$$\mu_p$$

$$\mu_n = 3.74 \text{ E}10$$

$$\lambda = 0.125 \mu$$

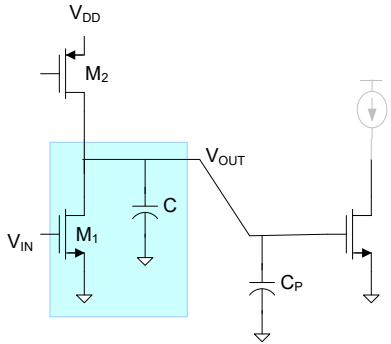
$$h_{\text{BOT}} = \frac{C_{\text{BOTn}}}{C_{\text{OX}}} = \frac{C_{\text{BOTp}}}{C_{\text{OX}}}$$

$$h_{\text{BOT}} = 0.31$$

$$h_{\text{SW}} = \frac{C_{\text{SWn}}}{\lambda C_{\text{OX}}} = \frac{C_{\text{SWp}}}{\lambda C_{\text{OX}}}$$

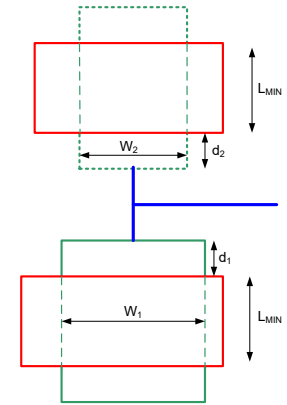
$$h_{\text{SW}} = 0.61$$

# How high can $I_0$ be?



$$I_0 = \frac{\omega_T}{1 + \left( 3h_{\text{BOT}} \left[ 1 + \frac{\mu_n}{\mu_p} \left( \frac{V_{\text{EB1}}}{V_{\text{EB2}}} \right)^2 \right] + h_{\text{SW}} \left[ 12 \frac{\lambda}{W_1} + 1 + \frac{\mu_n}{\mu_p} \left( \frac{V_{\text{EB1}}}{V_{\text{EB2}}} \right)^2 \right] \right)}$$

Consider a basic layout



Example: Consider the 0.25u TSMC CMOS Process

$$I_0 = \frac{\omega_T}{1 + \left( 3 \cdot 0.31 \left[ 1 + 4.1 \left( \frac{V_{\text{EB1}}}{V_{\text{EB2}}} \right)^2 \right] + 0.61 \left[ 12 \frac{0.125}{W_1} + 1 + 4.1 \left( \frac{V_{\text{EB1}}}{V_{\text{EB2}}} \right)^2 \right] \right)}$$

$$h_{\text{BOT}} = 0.31$$

$$h_{\text{SW}} = 0.61$$

$$I_0 = \frac{\omega_T}{1 + \left( 0.931 \left[ 1 + 4.1 \left( \frac{V_{\text{EB1}}}{V_{\text{EB2}}} \right)^2 \right] + 0.61 \left[ \frac{1.5}{W_1} + 1 + 4.1 \left( \frac{V_{\text{EB1}}}{V_{\text{EB2}}} \right)^2 \right] \right)}$$

$$\frac{\mu_n}{\mu_p} = 4.1$$

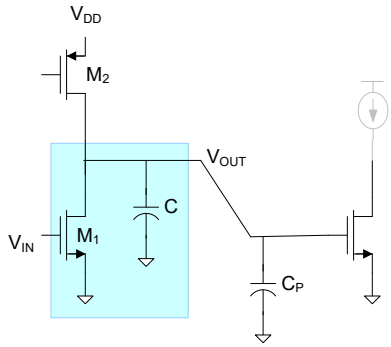
$$\mu_p$$

GATE  
term

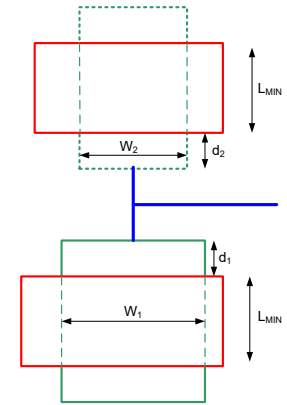
BOT term

SW term

# How high can $I_0$ be?



Consider a basic layout



Example: Consider the 0.25u TSMC CMOS Process

$$I_0 = \frac{\omega_T}{1 + \underbrace{\left[ 0.93 \left[ 1 + 4.1 \left( \frac{V_{EB1}}{V_{EB2}} \right)^2 \right] \right]}_{\text{BOT term}} + \underbrace{0.61 \left[ \frac{1.5}{W_1} + 1 + 4.1 \left( \frac{V_{EB1}}{V_{EB2}} \right)^2 \right]}_{\text{SW term}}}$$

GATE term
BOT term
SW term

If  $W_1 = 1.5\mu$  and  $V_{EB1} = V_{EB2}$

$$I_0 = \frac{\omega_T}{1 + (4.73 + 4.03)} = .102\omega_T$$

- Designer has control of  $V_{EB1}$  and  $V_{EB2}$
- The diffusion capacitance term can dominate the  $C_{GS}$  term
- The SW capacitance can be the biggest contributor to the speed limitations
- A factor of 10 or even much more reduction in speed is possible due to the diffusion parasitics and layout
- Maximizing  $W_1$  will minimize  $I_0$  but power will get very large for marginal improvement in speed



Stay Safe and Stay Healthy !

**End of Lecture 35**